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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 1632

Norio KIMURA et al.

Attorney Docket No. 2001-0660A

Serial No. 09/864,208

Group Art Unit 1763

Filed May 25, 2001

Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS AND SUBSTRATE POLISHING METHOD

MAIL STOP: AF

## **AMENDMENT AFTER FINAL REJECTION**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE UNDER 37.CFR1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1700

Sir:

In response to the Office Action of May 3, 2006, the period for response to which having been extended by two months to October 3, 2006, kindly amend the above-referenced U.S. patent application as follows:

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS DAPER TO SUPPOSIT ACCOUNT HE IS SHOWN.